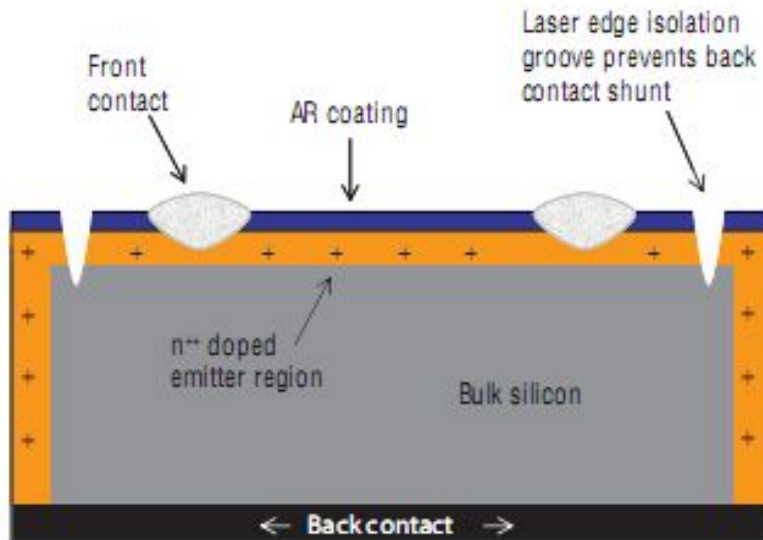


太阳能电池刻蚀激光设备

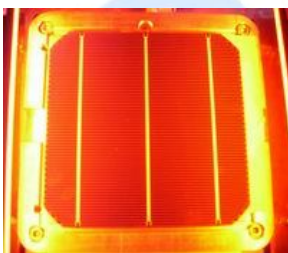
Laser Edge Isolation



Without edge isolation groove, current shunt occurs between front and back contact through the ion diffusion layer.



该机型应用于硅片的刻蚀及边绝缘。



Specification:

适用硅片单晶/多晶硅片: 125mm×125mm/156mm×156mm

硅片厚度(μm)150-220

破片率< 0.2%

运行时间 >97%

CCD 自动识别校正

低碎片率;

可移动式储存篮

模块化设计:inline / stand alone 均可

For more details, please contact dr@drlaser.com.cn; 86-27-87922379.